

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: KATO, et al.  
Serial No.: 09/766,596  
Filed: January 23, 2001  
For: VACUUM PROCESSING APPARATUS AND OPERATING METHOD THEREFOR

SUPPLEMENTAL PRELIMINARY AMENDMENT

Assistant Commissioner for Patents  
Washington, D.C. 20231

May 29, 2001

Sir:

Prior to examination of the above-identified application, and supplementing the Preliminary Amendment filed January 23, 2001, please amend the above-identified application as follows:

IN THE CLAIMS

✓  
Please cancel claims 1-26 without prejudice or disclaimer, and add the following new claims to the application:

Sub C1  
27. ~~A conveyor system for processing substrates in~~  
plural vacuum processing chambers, the conveyor system including:

1.  
a loader;  
a vacuum loader; and  
double lock chambers, having a loader side and a vacuum loader side, and having a gate valve for said loader side and another gate valve for said vacuum loader side,